



PATENT APPLICATION

In re Application of:

Shigeyuki UZAWA et al.

Application No.: 09/864,309

Filed: May 25, 2001

For: EXPOSURE APPARATUS, COATING/
DEVELOPING SYSTEM, DEVICE
MANUFACTURING SYSTEM, DEVICE
MANUFACTURING METHOD,
SEMICONDUCTOR MANUFACTURING
FACTORY, AND EXPOSURE APPARATUS
MAINTENANCE METHOD

)
: Examiner: R. A. Jarrett
)
: Group Art Unit: 2125
)
: Confirmation No.: 2803

) February 5, 2004

Mail Stop RCE

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

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INFORMATION DISCLOSURE STATEMENT

Sir:

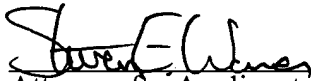
In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed PTO-1449 form. Copies of these documents are also enclosed.

Applicants request that the above information be considered by the Examiner and that a copy of the enclosed PTO-1449 form be initialed and returned indicating that such information has been considered.

No fee is believed to be due with the filing of this paper. Nevertheless, the Commissioner is authorized to charge Deposit Account No. 06-1205 should any fee be deemed necessary for filing this paper.

Applicants' undersigned attorney may be reached in our Washington D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



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